

# Advanced Control Systems (Examples)

T. H. Lee

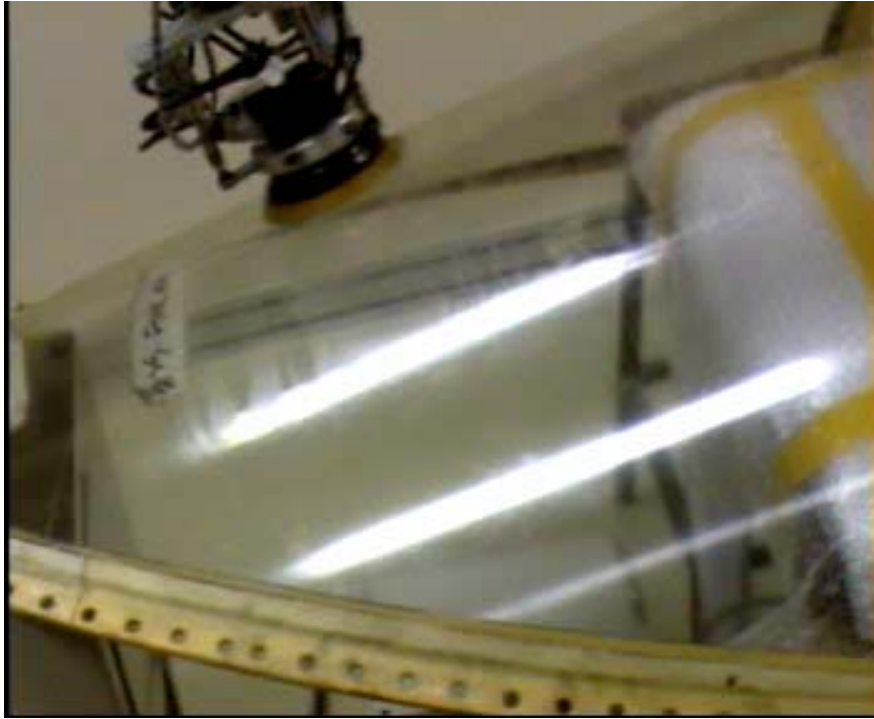
(in collaboration with colleagues & students)

Centre for Intelligent Control

(C&S, M&A, ACT Labs)

Department of Electrical & Computer Engineering  
National University of Singapore

# aircraft canopy polishing



Advanced Control  
Systems projects:  
prototypes  
being refined in  
different stages

Fukuda & co-workers (Nagoya)  
Lewis & co-workers (Arlington)  
Moore & co-workers (Utah)  
Grimble & co-workers (Strathclyde)  
Tso & co-workers (Hong Kong)  
C.W. de Silva & co-workers (UBC)



# Other Systems (at CIC, NUS)

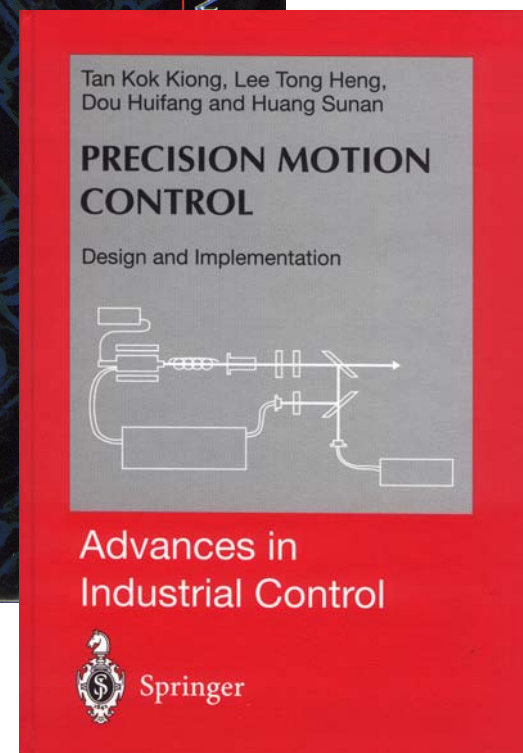
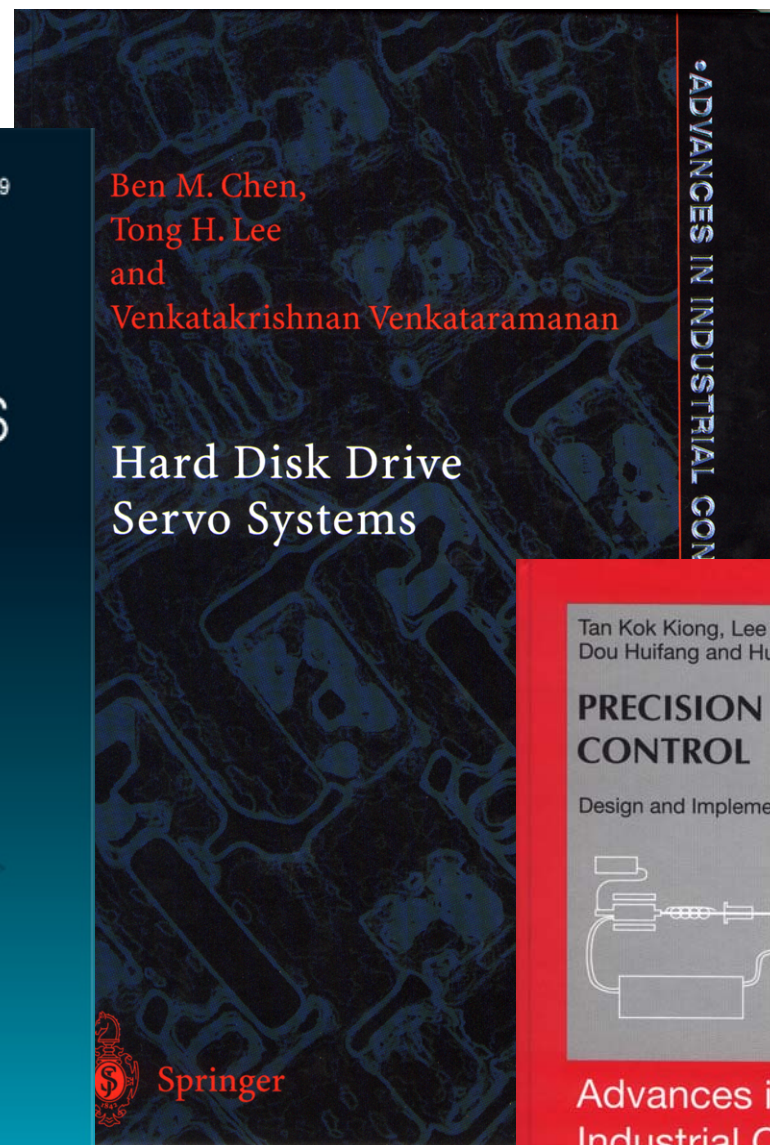
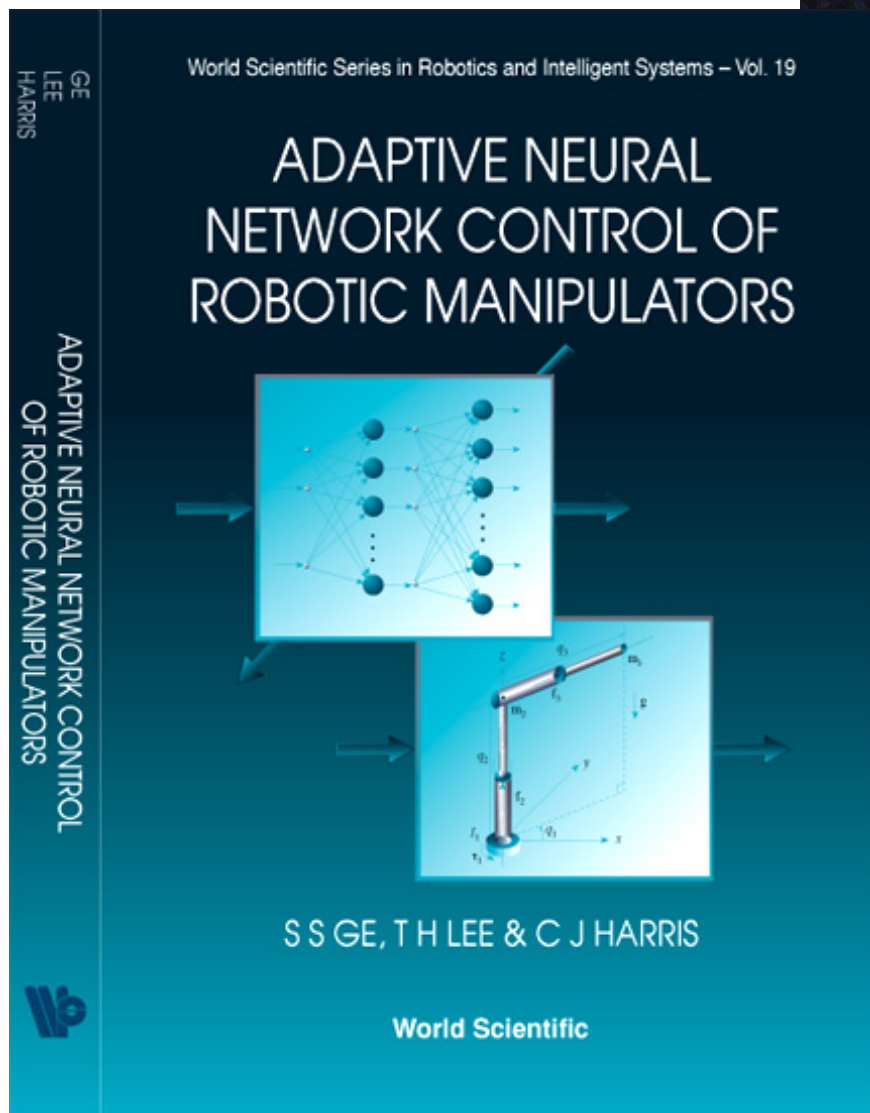


Gladiator Robots

Some of the other fun things our students work on...

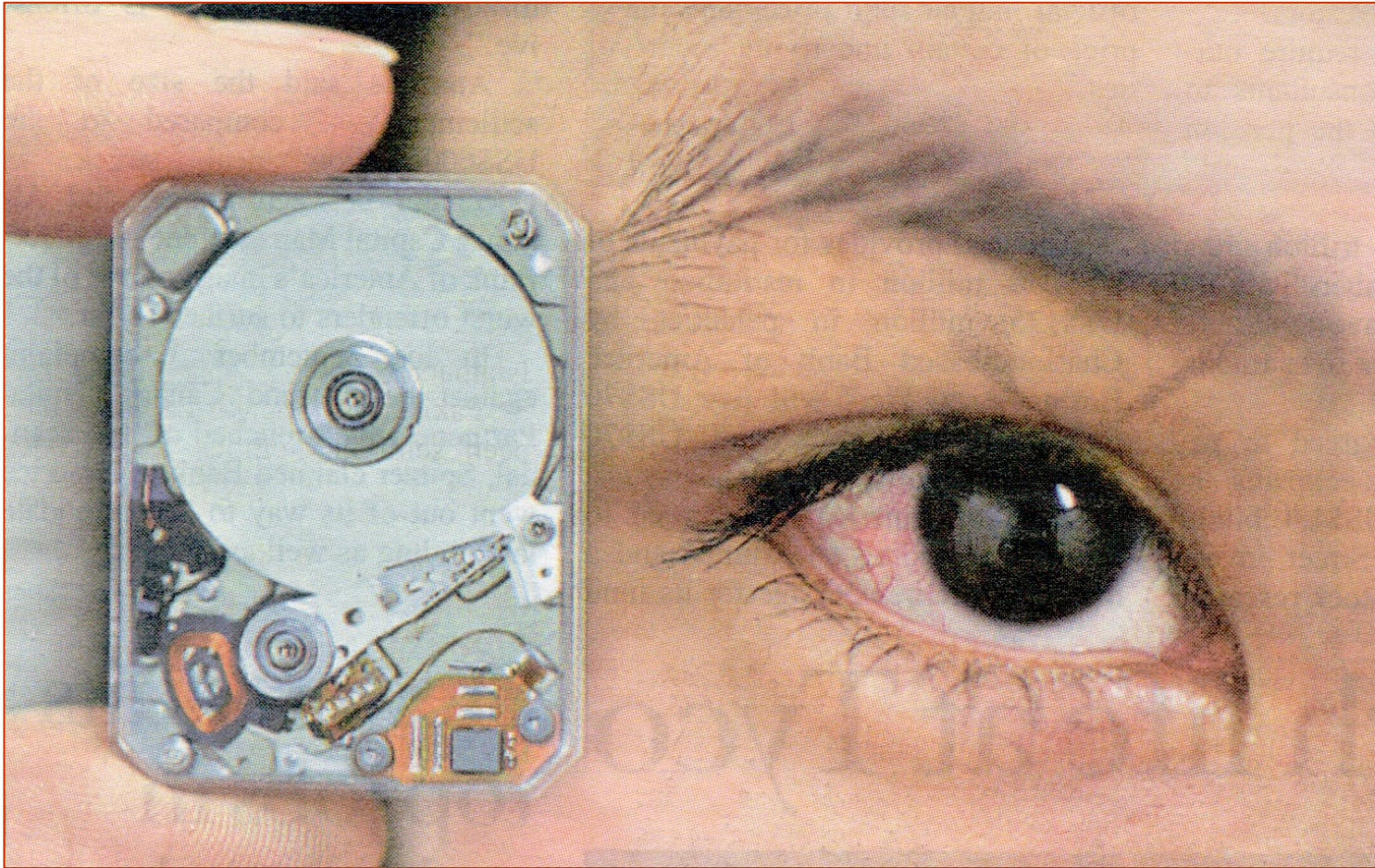


Pole-balancing Robot



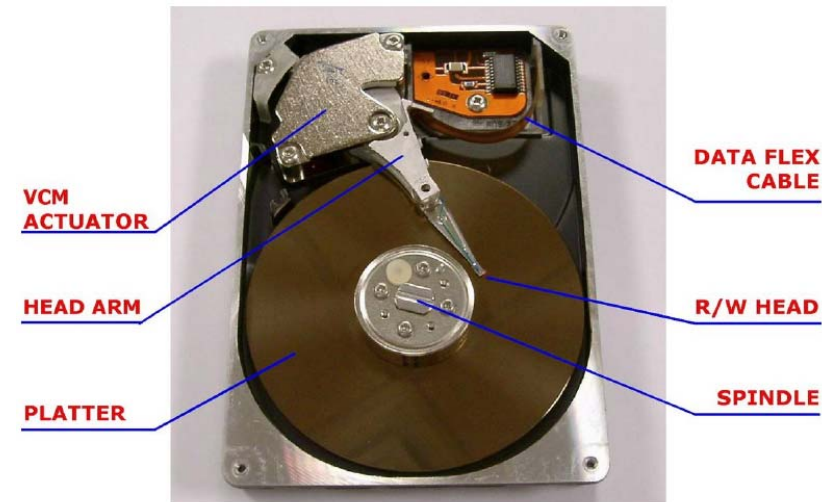
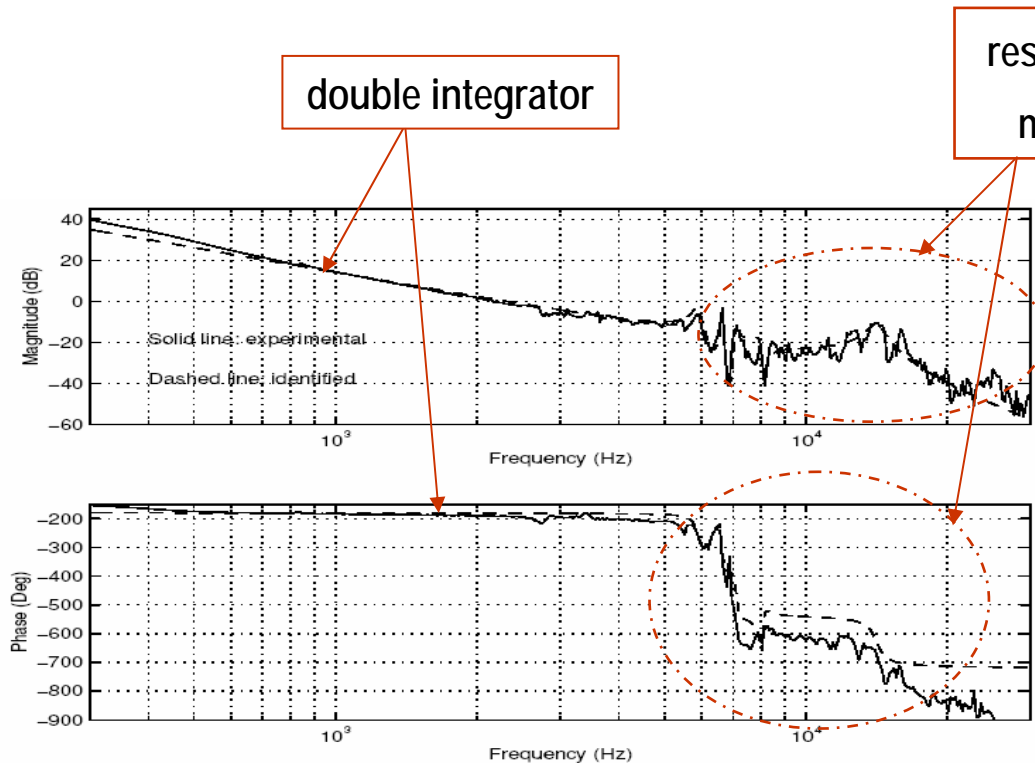


## Microdrives (Toshiba 0.85-inch HDD, 4 GB)



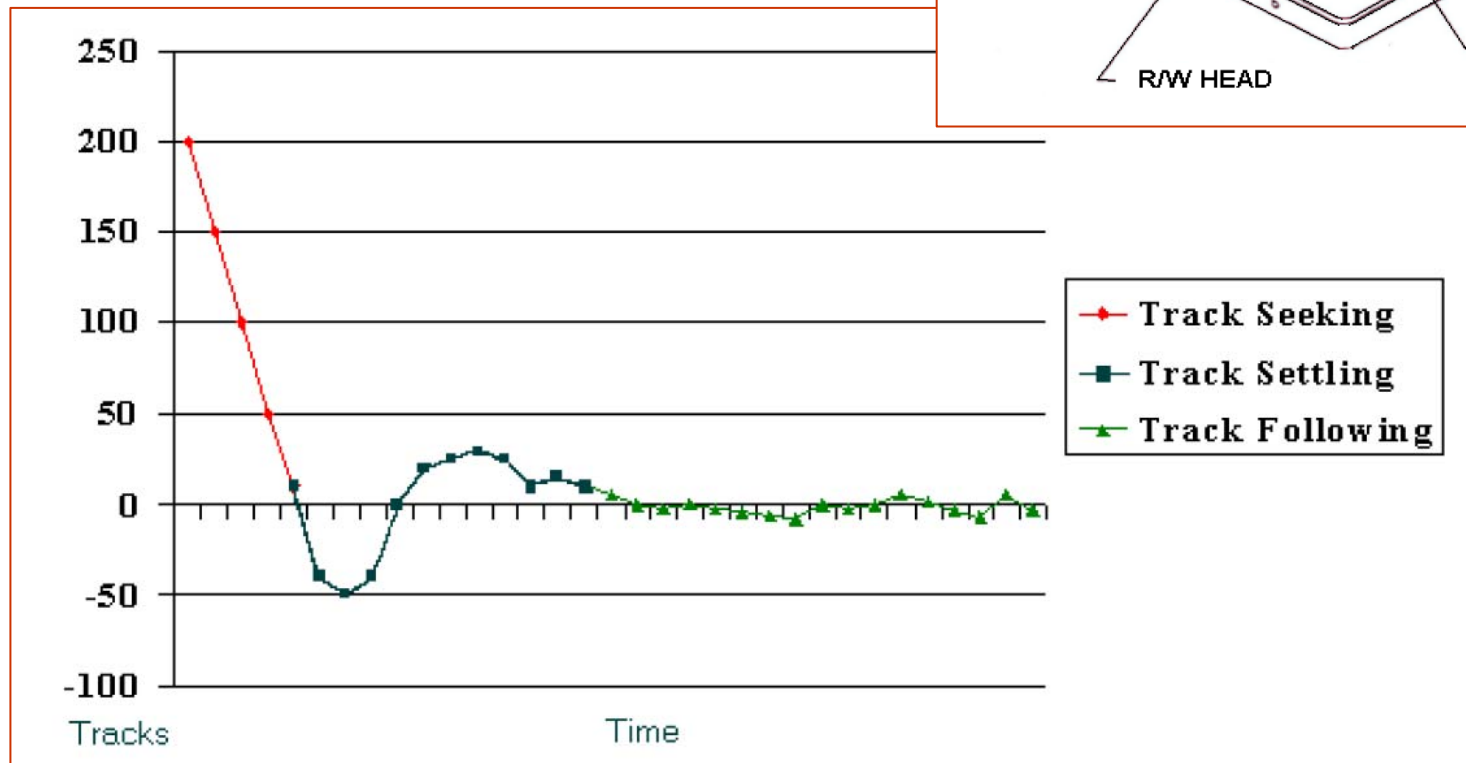
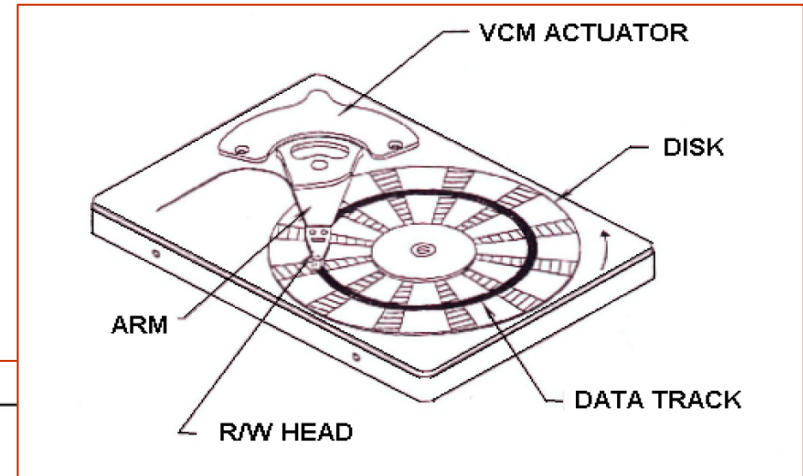
# Modeling and Identification

Basically, the HDD VCM actuator displays both linear and nonlinear features in its dynamic model. At the low-frequency range, it behaves as a double integrator (linear), a typical behaviour of servomechanism, and at the high frequencies, it has many resonance modes. Nonlinearities associated with the system are friction and those from data flex cable...



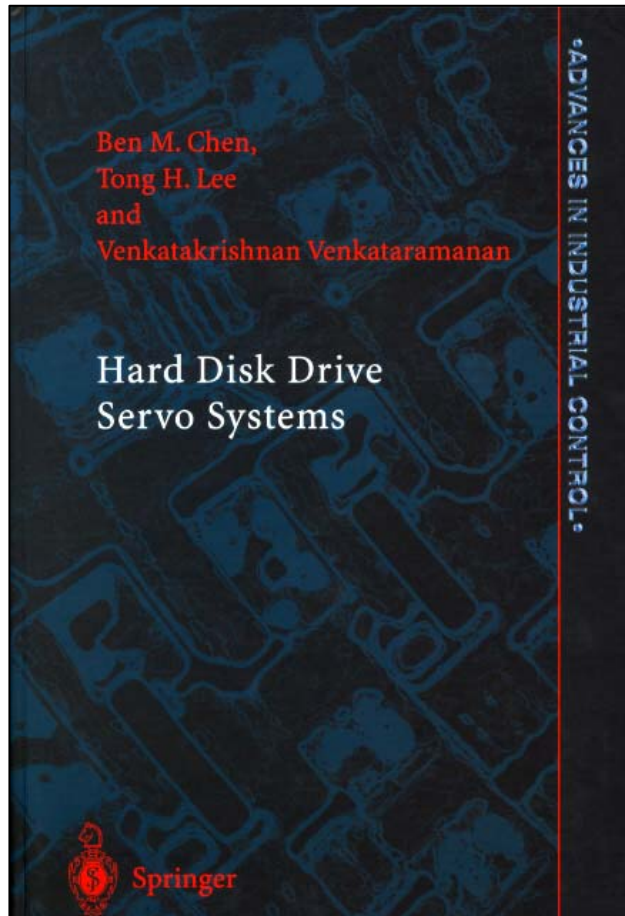
# HDD Control Systems

An HDD control system involves two main tasks: track following (**linear control**) and track seeking (**nonlinear control**)...

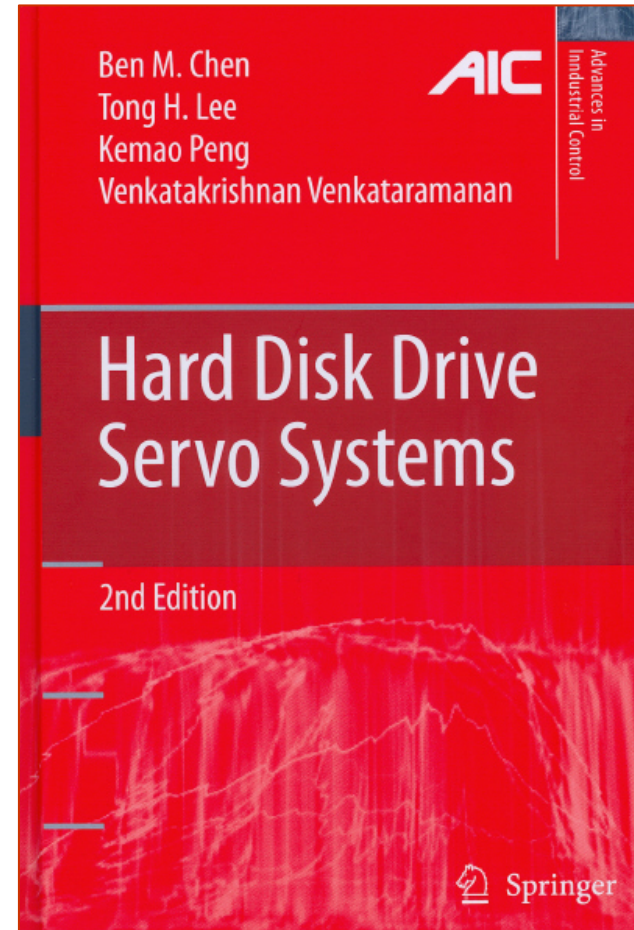




## Details described in:



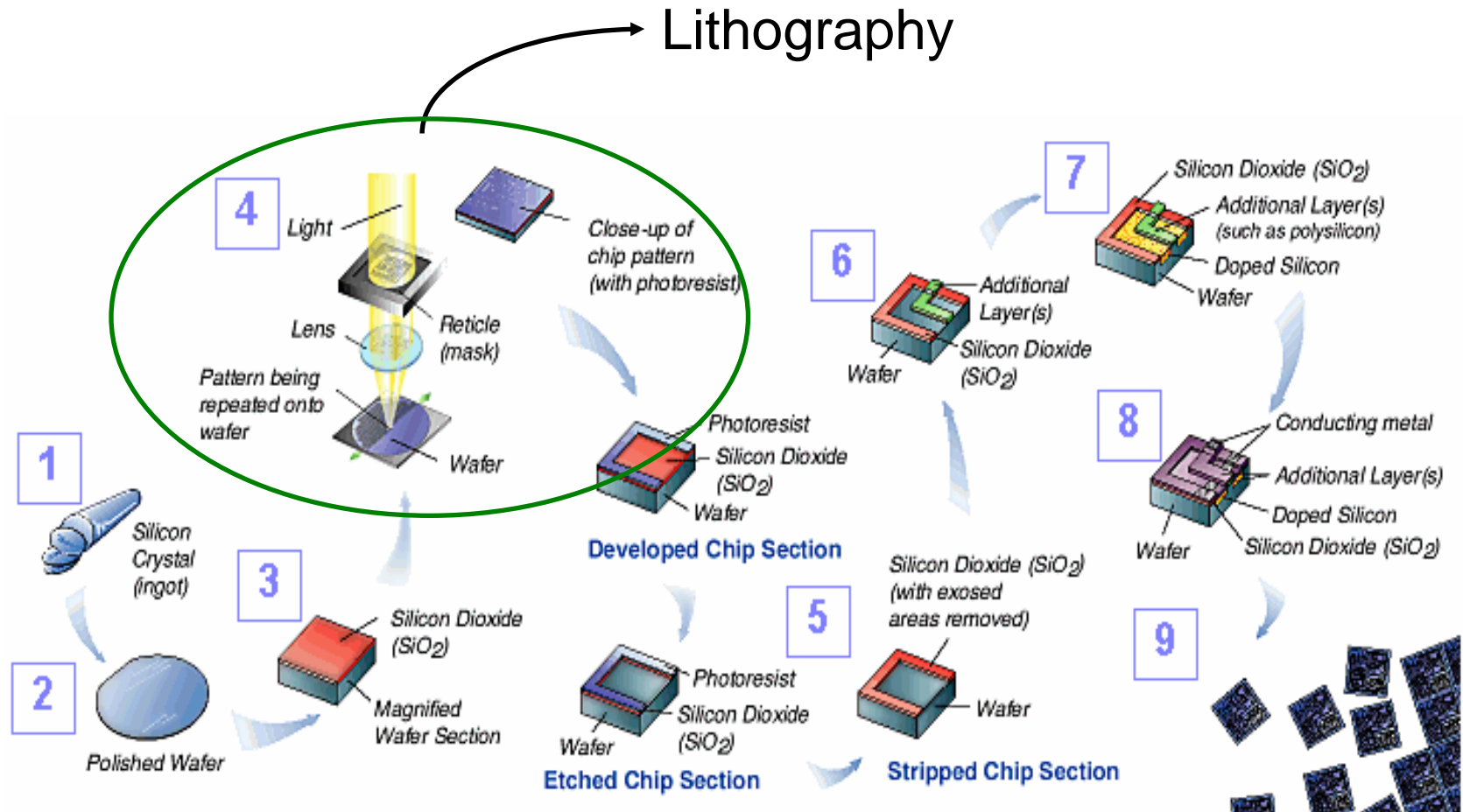
**2002**



**2006**



# Semiconductor Manufacturing Process



Source: Sematech, Inc.

# International Technology Roadmap for Semiconductors: 2002 Update

## Grand Challenge:

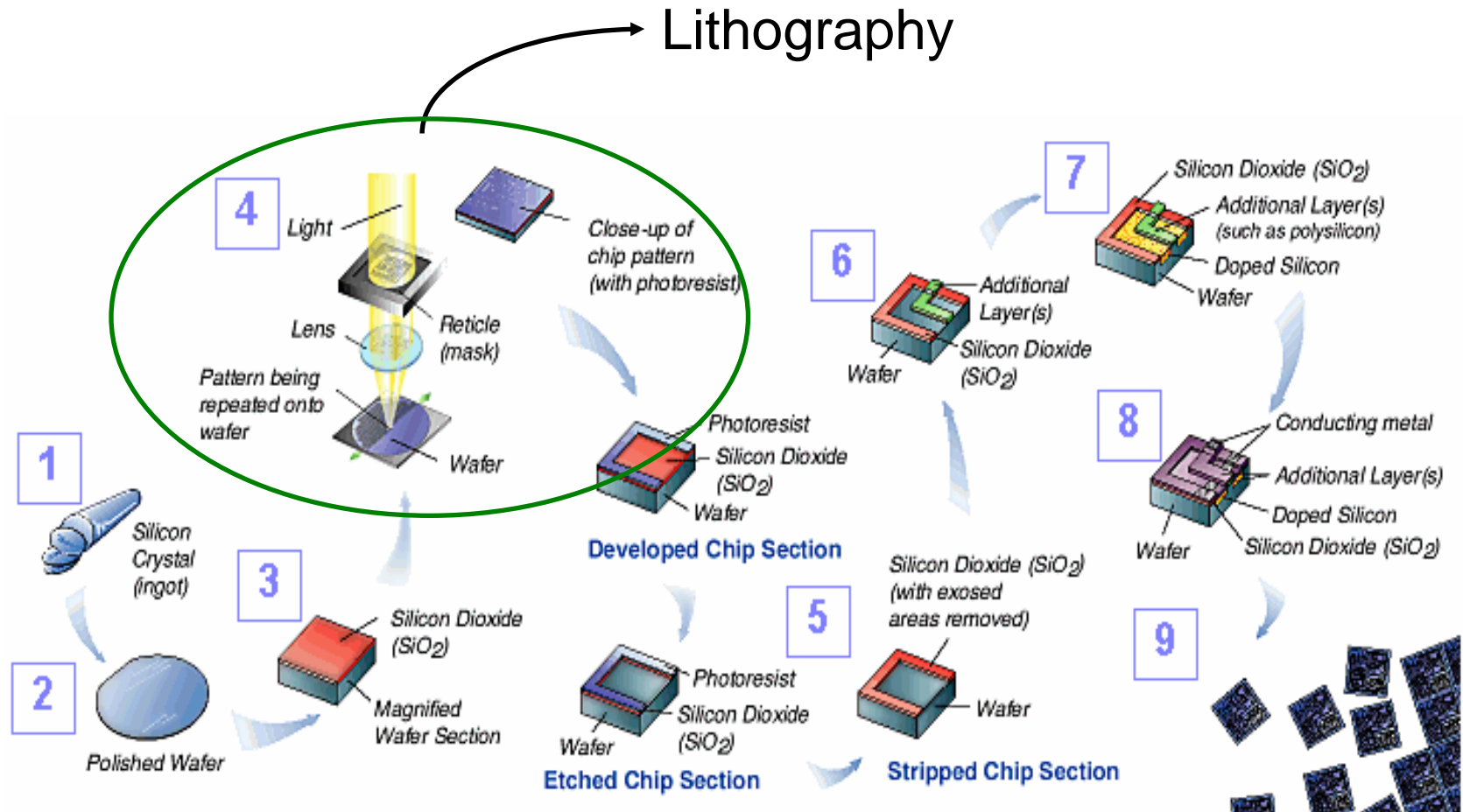
Process control, particularly for overlay and linewidths, also represents a major challenge. It is unclear whether metrology, which is fundamental for process control, will be upgraded adequately to meet future requirements.

# International Panel on Future Directions in Control, Dynamics and Systems, AFOSR, 2002:

...use of **control** is critical to future progress in the semiconductor sector. Modeling plays a crucial role and control techniques must make use of more **in-situ measurements** to control at a variety of temporal and spatial scales.



# Semiconductor Manufacturing Process

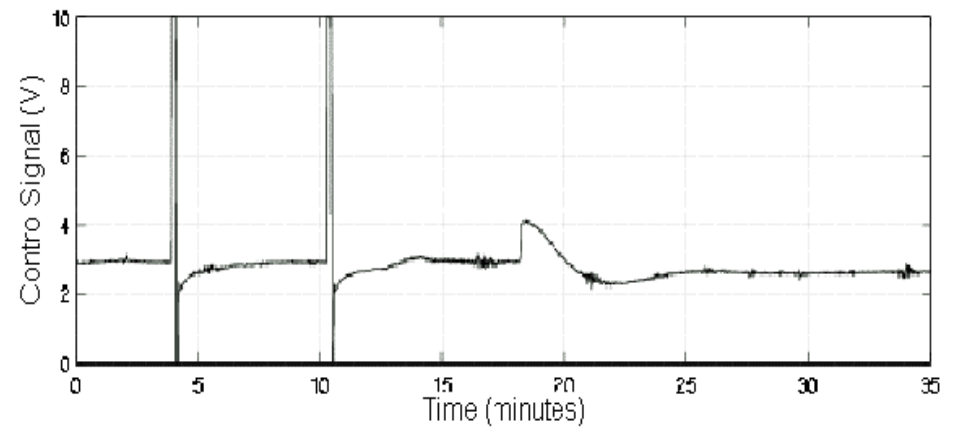
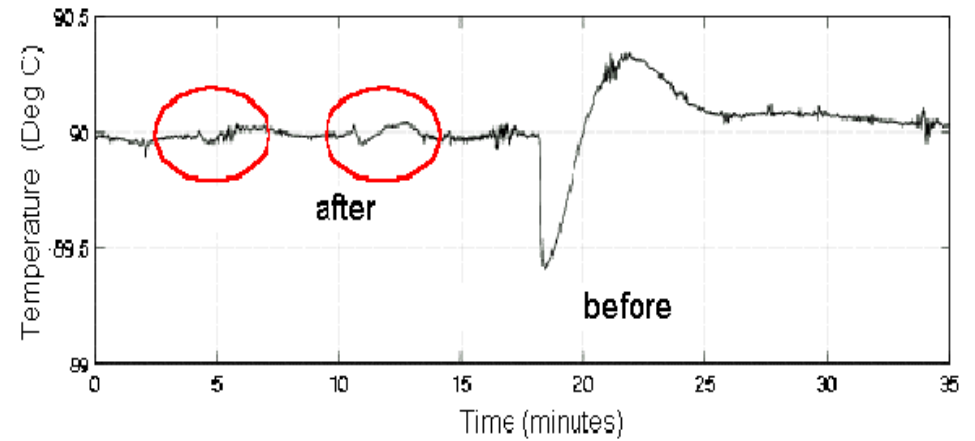
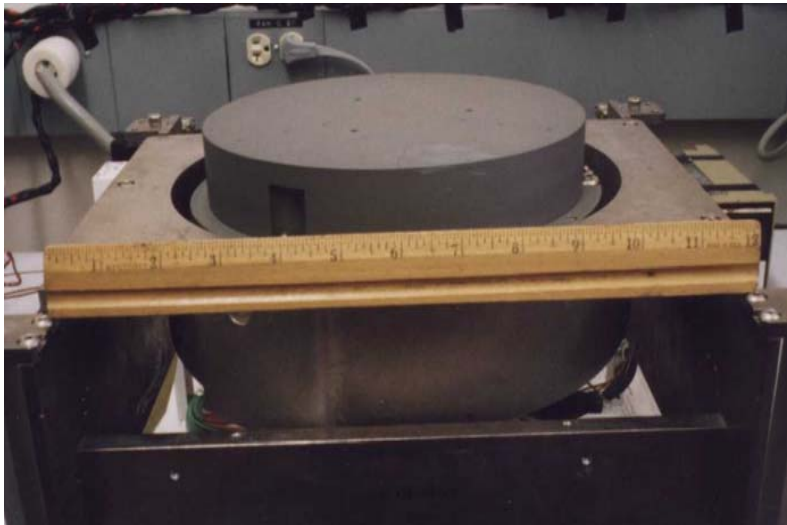


Source: Sematech, Inc.

# Scope

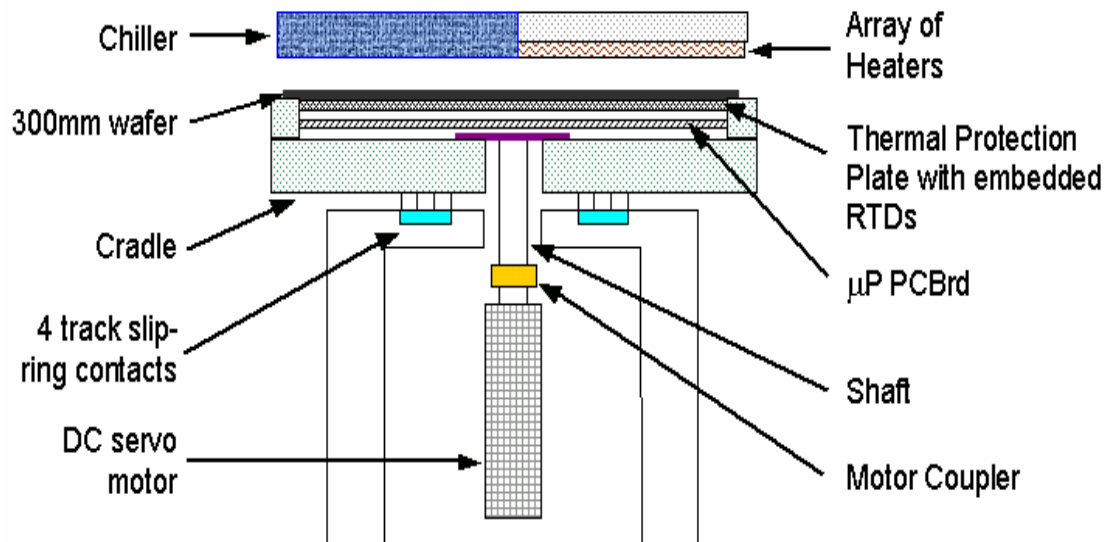
- Issues in Lithography:
  - Temperature Control
  - Photoresist Thickness
  - Wafer Warpage

# Temperature Control

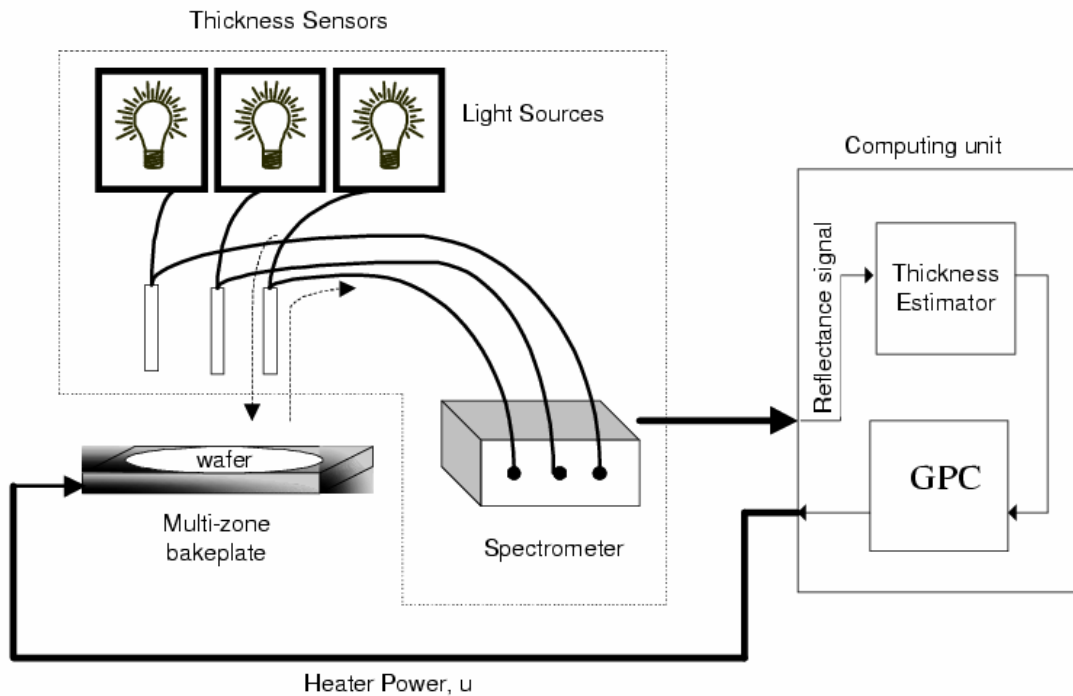




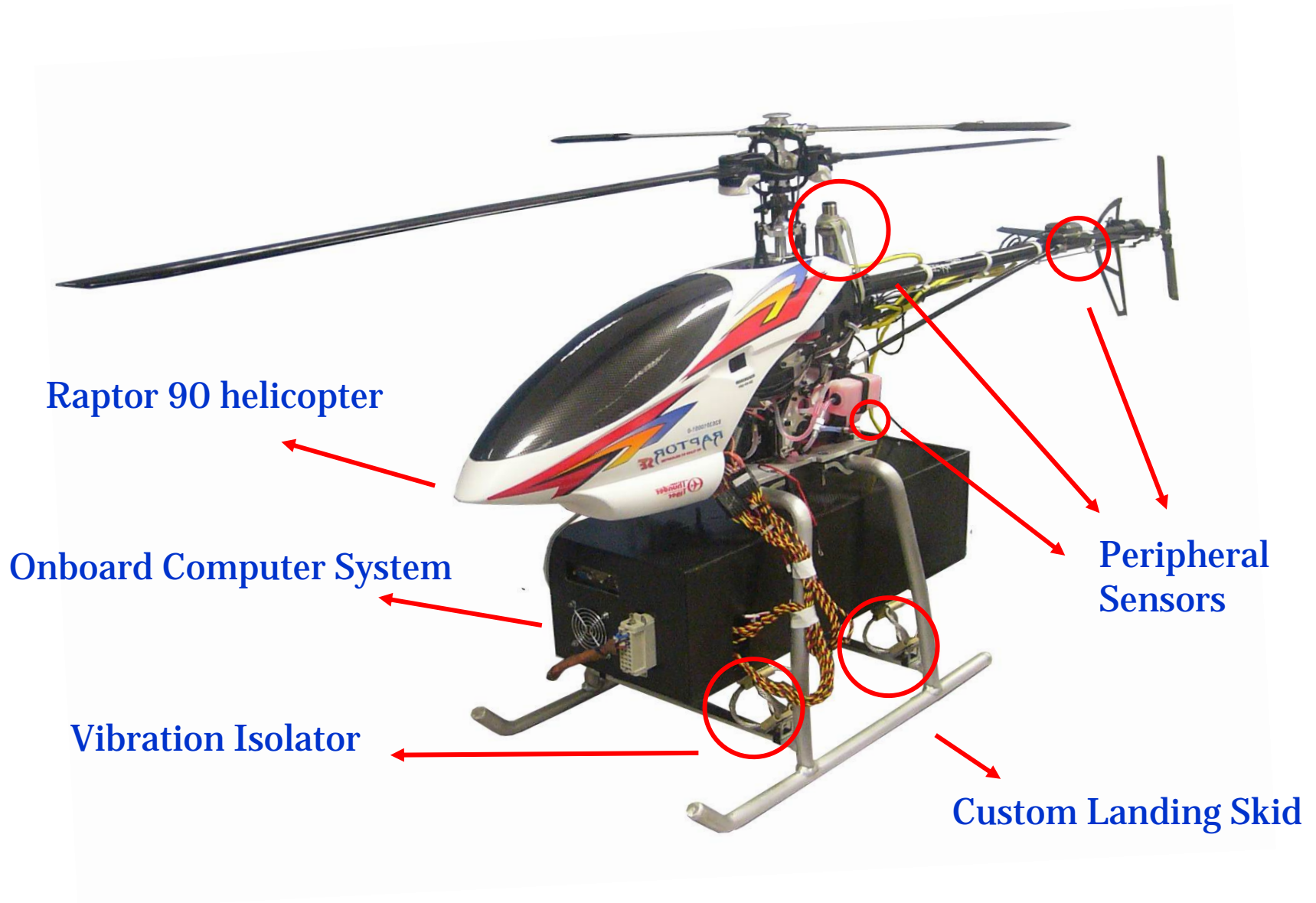
# New Thermal System Design



# In-situ thickness measurement



# UAV (Helicopter) control system





# UAV System

## Onboard

- inertial measurement
- servo driving
- automatic control
- communication
- data logging



***Helicopter***

***Communication***



***Ground Station***

## Ground Station

- data transferring (background)
- user interface (foreground)

# Linear State-Variable Model

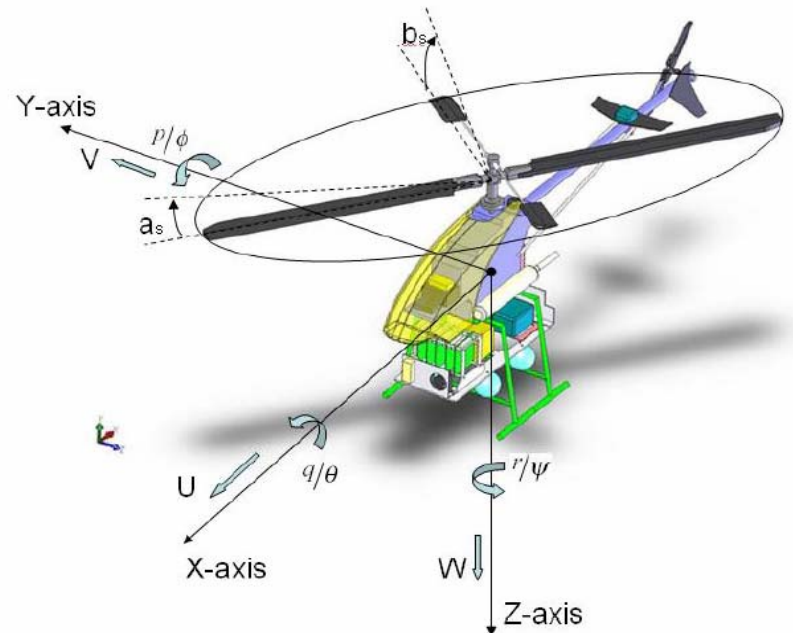
- Linear model for helicopter under specific flight condition

$$\dot{\mathbf{x}} = \mathbf{A}\mathbf{x} + \mathbf{B}\mathbf{u}$$

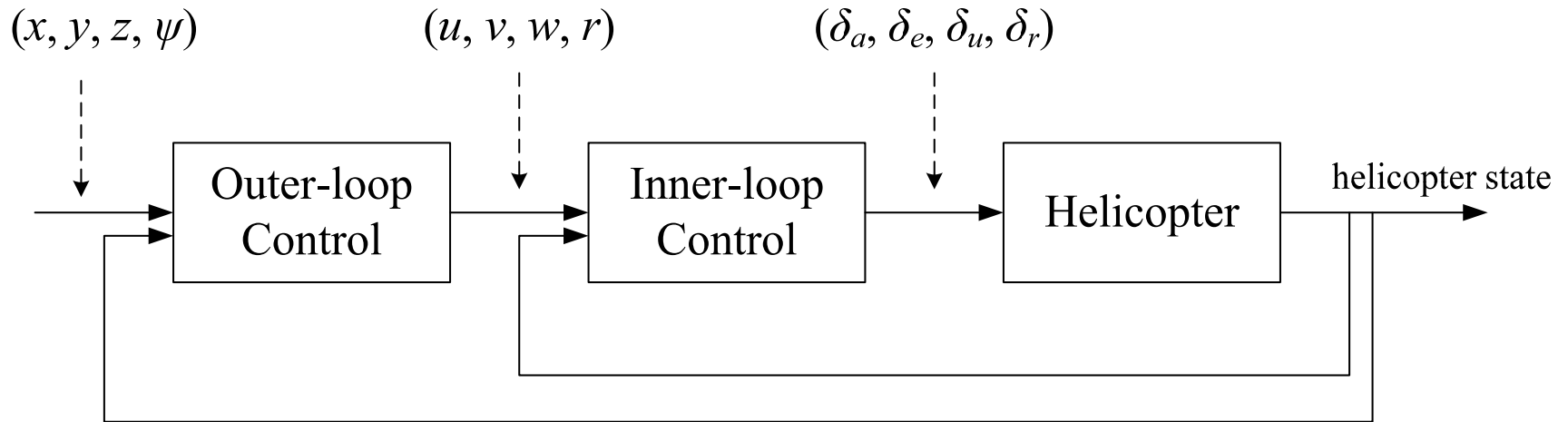
where

$$\mathbf{x} = (u, v, p, q, \phi, \theta, a_s, b_s, w, r, r_f, \zeta_a, \zeta_e, \zeta_u)$$

$$\mathbf{u} = (\delta_a, \delta_e, \delta_u, \delta_r)$$

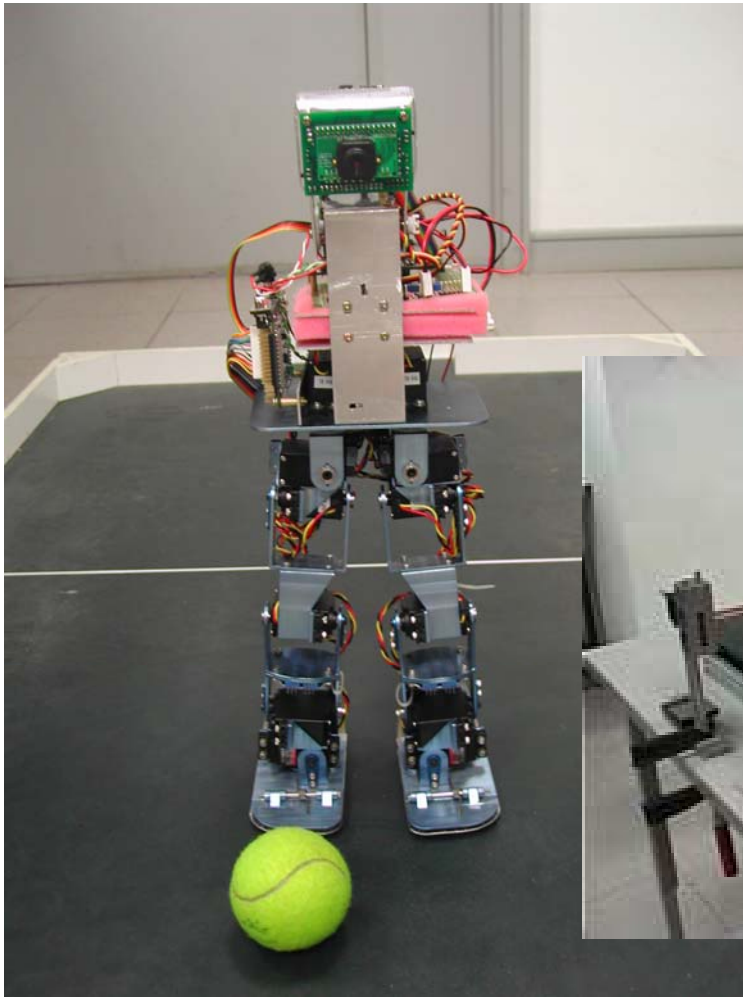


# UAV (Helicopter) Control



- $x, y, z$  — position of the helicopter respective to ground frame (North-East-Down frame)
  - $u, v, w$  — velocity of helicopter along axis in body frame
  - $\phi, \theta, \psi$  — roll, pitch and heading angle of helicopter (NED frame)
  - $p, q, r$  — roll, pitch and yaw rate of helicopter along axis in body frame
  - $\delta_a, \delta_e, \delta_u, \delta_r$  — control signal for aileron, elevator, collective pitch and rudder
- helicopter state —  $(x, y, z, u, v, w, \phi, \theta, \psi, p, q, r)$

# MORE SYSTEMS (at CIC, NUS)



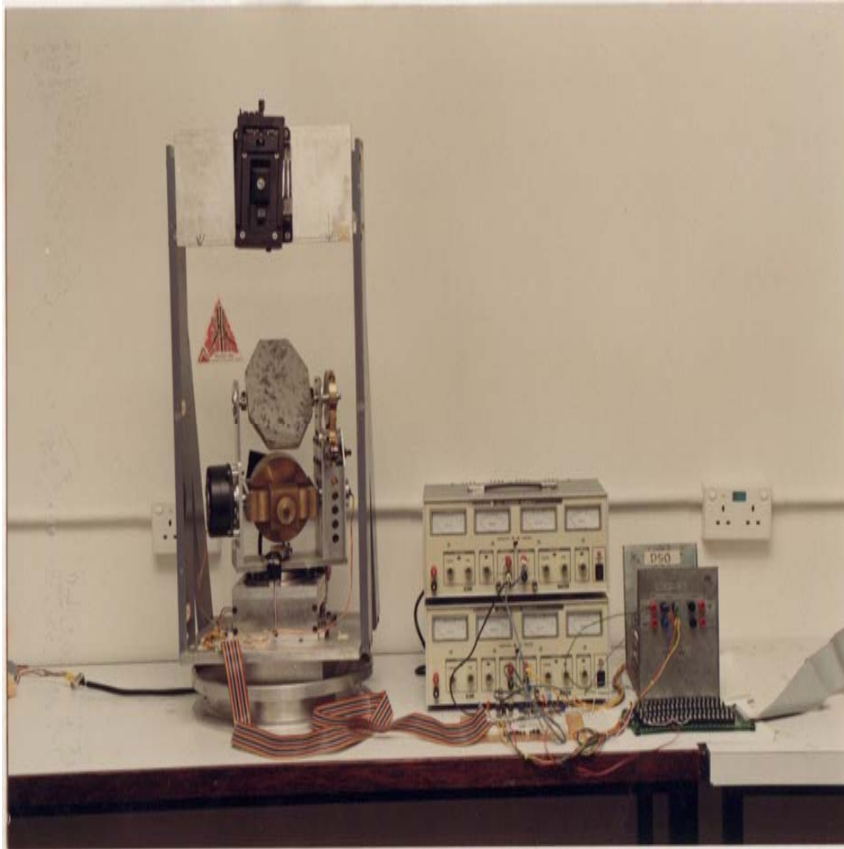
Ge & students



KKTan & students

Prahlad & students (won 1<sup>st</sup> Prize at  
FIRA Competition, Austria; 7 Oct 2003)

# MORE SYSTEMS (at CIC, NUS)



Gyro-stabilized line-of-sight pointing system

